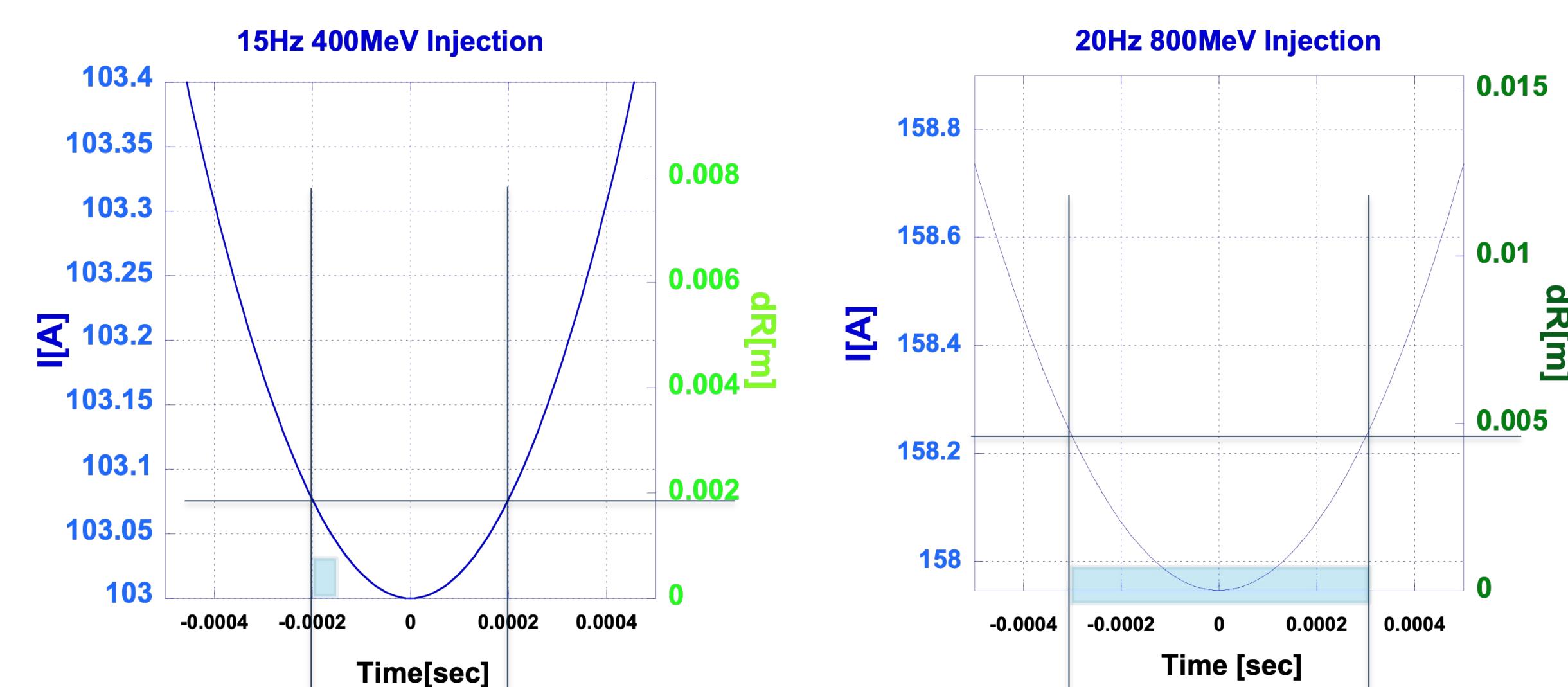


Flattening the field during injection in the Fermilab booster using dipole corrector

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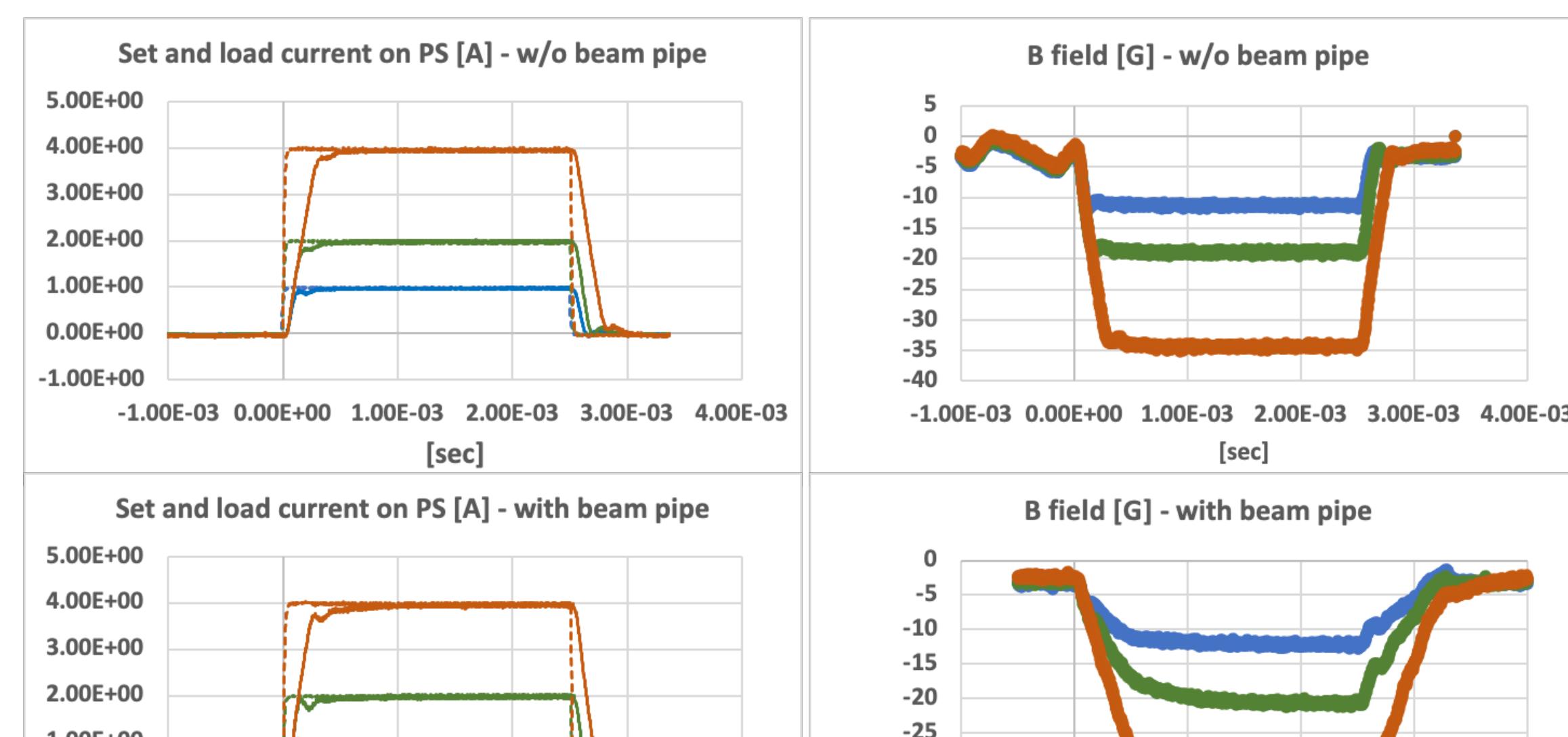
Goal

(1) Flattening of the net bending during injection using dipole correctors, and (2) Using a new system based on an Altera FPGA board, reduction of the cycle-to-cycle bending field variation caused by current jitter in the Gradient Magnet Power Supply (GMPS).

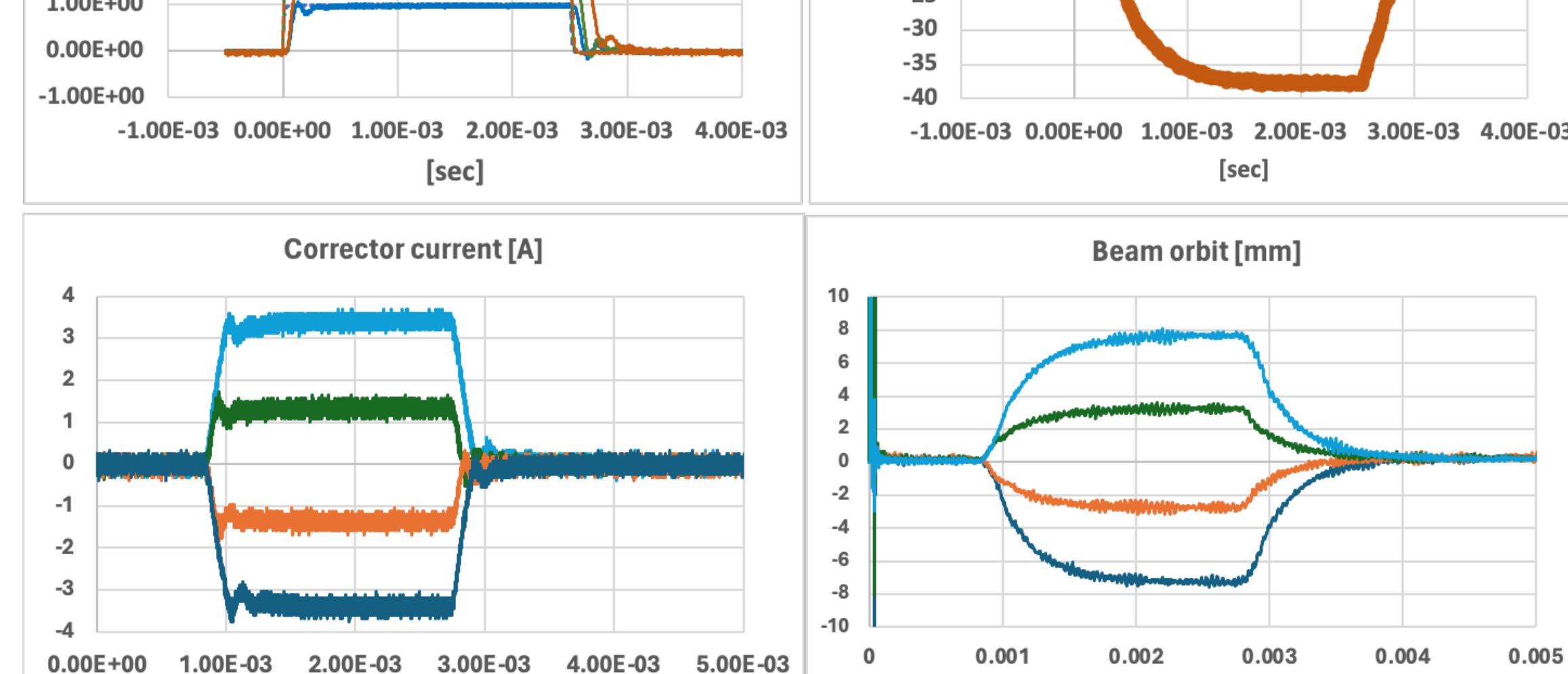


Corrector field with slew rate and Eddy current effect

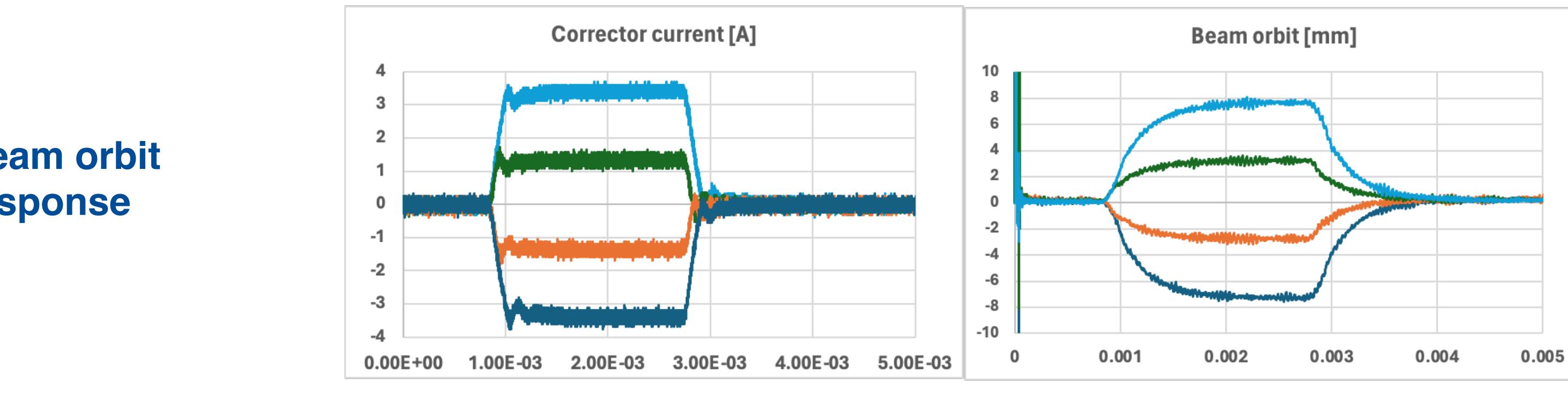
Corrector B field without beam pipe



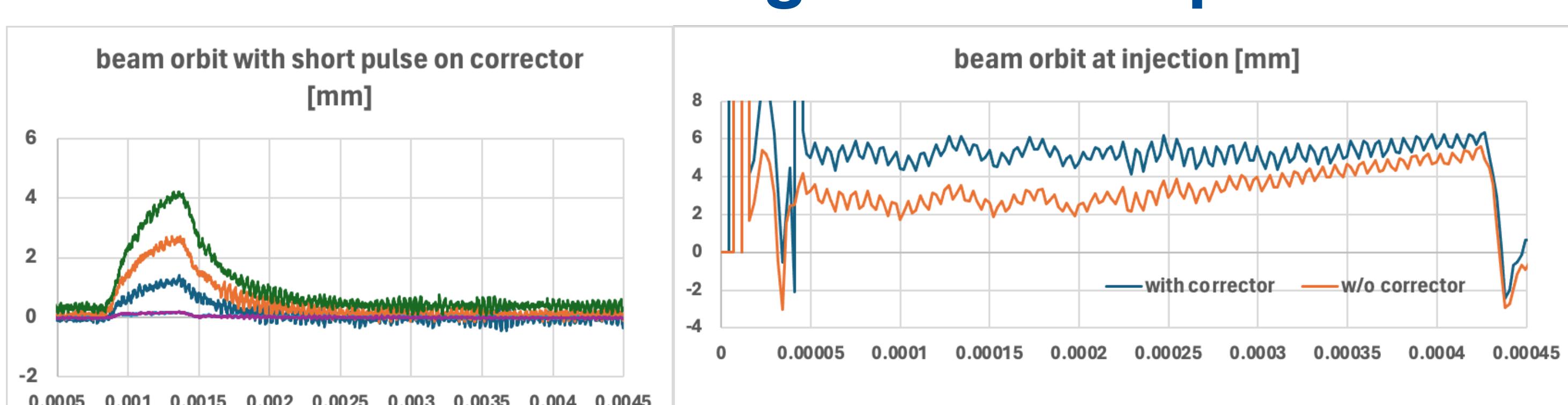
Corrector B field With beam pipe



Beam orbit response



Effective B field flattening with short pulse

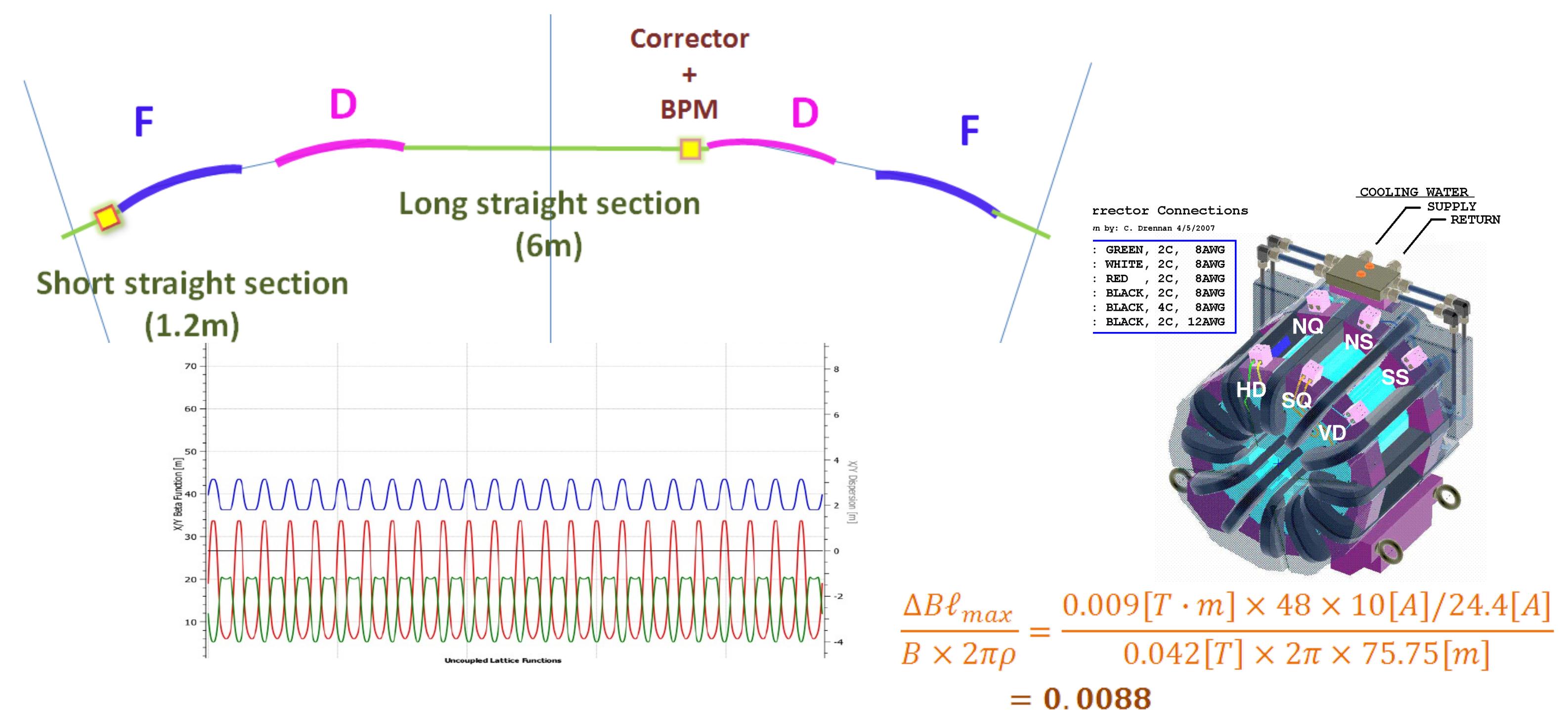


CONCLUSION

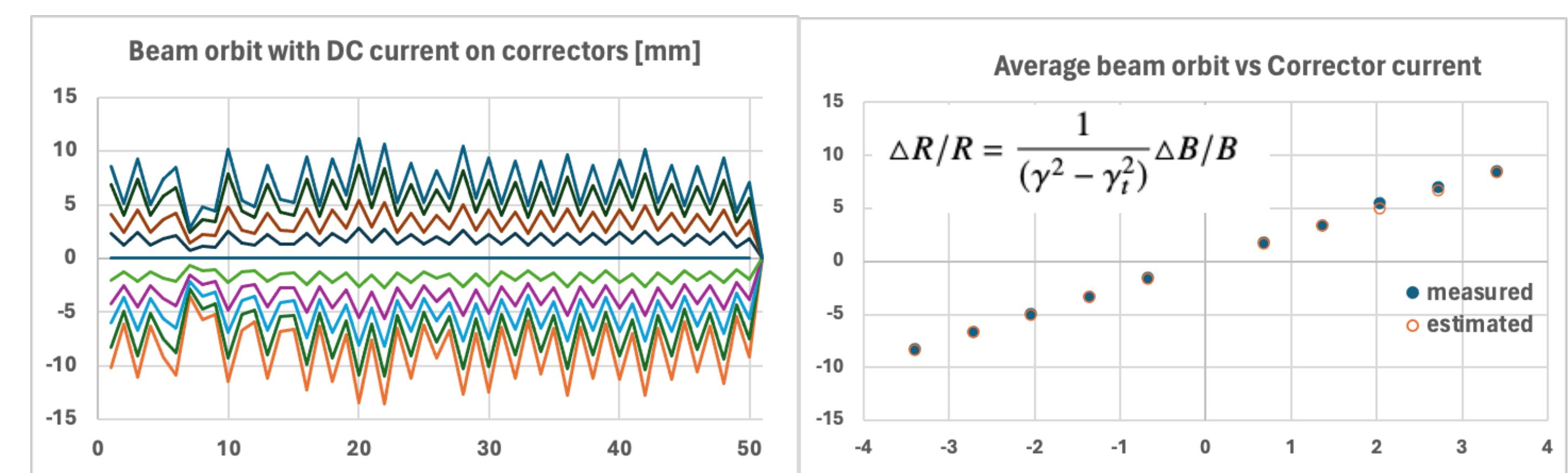
In preparation for the upcoming PIP-II operation, efforts were made to flatten the effective bending field at injection. During beam studies, the orbit response to the dipole corrector field was measured. Due to limitations in the power supply, the output voltage was restricted, thereby reducing the slew rate. Additionally, the corrector field was observed to be affected by the Eddy current effect. Using the limited field response, the bending field was canceled and resulting in a change in orbit execution of less than 1mm.

Further beam studies revealed two additional primary issues. Firstly, during normal operation, the beam orbit moved more than 10 mm within the first 1 millisecond of injection. Secondly, the bending fields exhibited jitter of more than 0.1%, causing the beam orbit to fluctuate beyond +/- 5mm. To address the field jitter, a feedforward approach utilizing an FPGA module was implemented, resulting in a reduction of jitter to less than half of its original magnitude.

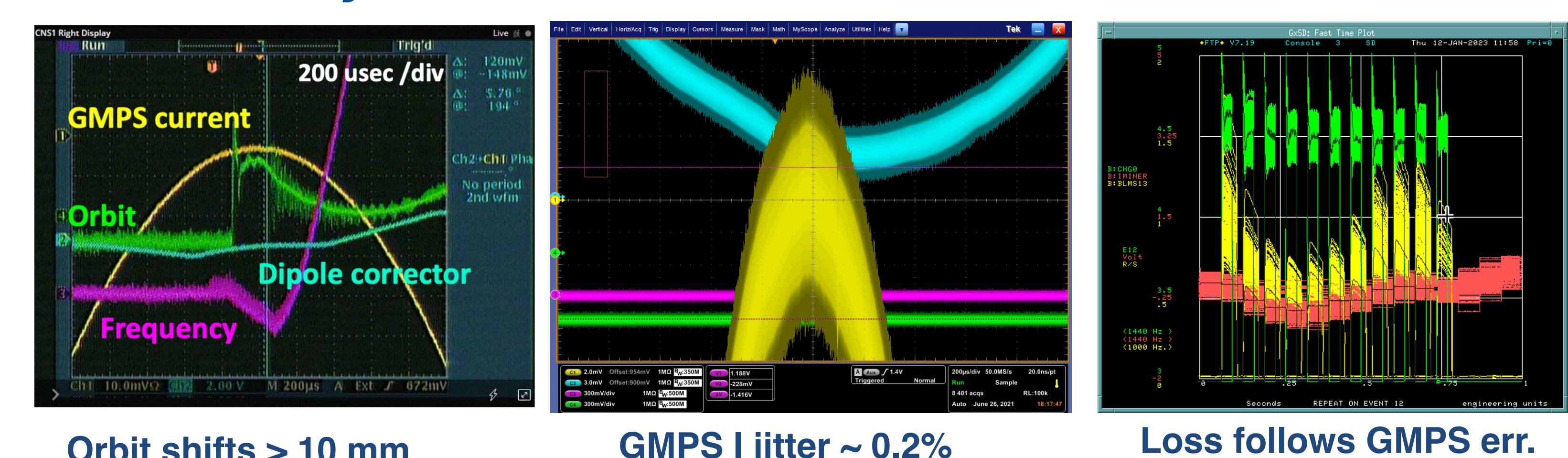
48 correctors in the Booster



Dipole corrector current vs Beam position

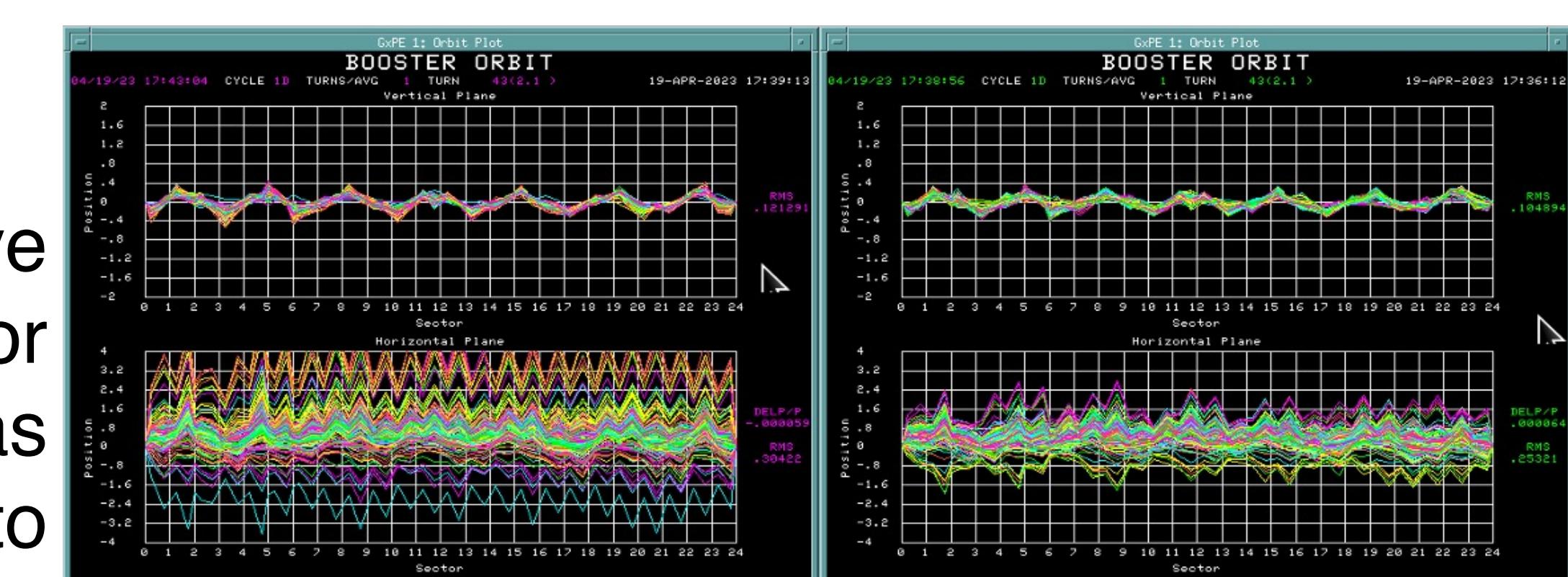
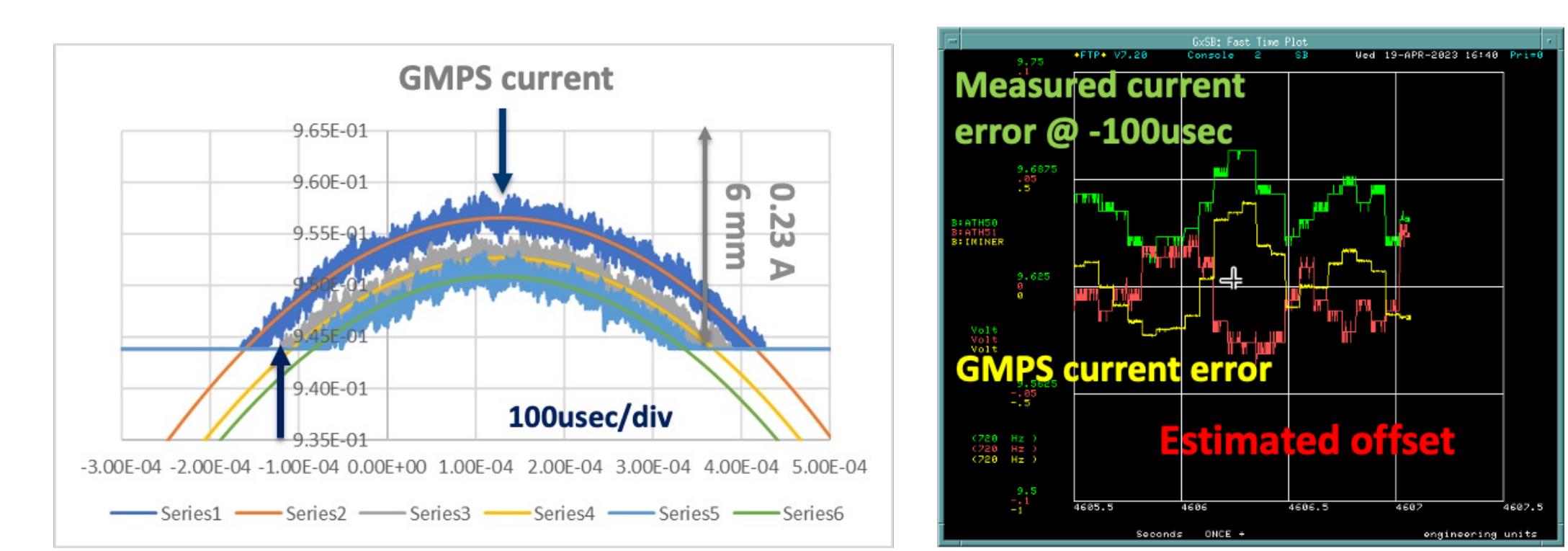


Beam at injection - other issues



Bending field amplitude jitter and control with FF

- 1: Measure current 100 usec before injection
- 2: Estimate required offset
- 3: Send the offset to correctors



ACKNOWLEDGEMENTS

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